

Title (en)

METHOD AND DEVICE FOR OPERATING A UV-RADIATION SOURCE

Title (de)

VERFAHREN UND VORRICHTUNG ZUM BETRIEB EINER UV-STRAHLENQUELLE

Title (fr)

PROCEDE ET DISPOSITIF POUR L'EXPLOITATION D'UNE SOURCE DE RAYONNEMENT UV

Publication

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Application

EP 01925387 A 20010307

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Abstract (en)

[origin: WO0175936A1] The invention relates to a method for operating a UV-radiation source of the low-pressure gas discharge type. Said method comprises the following steps: - impingement of at least one heating coil with a heating voltage until the temperature of said coil has been increased; - impingement of the heating coil with a starting voltage in order to induce a gas discharge; - maintenance of the gas discharge by the application of a maintaining voltage and the disconnection of the heating voltage after the gas discharge has been started; in addition the following steps are preferably executed at any point in the method: - interrogation of an identification element that is connected to the UV-radiation source and - if the response to the interrogation is negative, prevention or interruption of the operation, - if the response to the interrogation is positive, authorization of the operation. The invention also relates to a UV-radiation source comprising a base body (20) and at least one connection zone which bears a number of electric connections (24, 25; 26, 27), whereby an identification element (28) that can be interrogated electrically is connected to the base body (20); and to a UV-disinfection facility for fluids, in particular for water or waste water, said facility comprising at least one UV-radiation source and an electric control and supply circuit that is located at a distance from the radiation source, whereby the control and supply circuit comprises an interrogation unit which is suitable for verifying the presence of an identification element which is optionally assigned to the UV-radiation source(s).

IPC 1-7

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Citation (search report)

See references of WO 0175936A1

Citation (examination)

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